

Special Issue

Micro and Nano Abrasive Machining

Message from the Guest Editor

The application of micro and nano scale manufacturing was established during the development of the transistor in the late 1940s. In this Special Issue addressing micro and nano abrasive processing, the publishers invite you to submit research papers, review, case studies, and technical notes on the rapid development of manufacturing processes at the micro and nanoscale that are focused on machining and grinding operations. Authors are invited to contribute experimental, computational, theoretical, and practical applications of machining and grinding at the micro and nanoscales. Keywords:

- micro abrasives
- nano abrasives
- micro grinding
- nano grinding
- abrasives
- nanotechnology
- microtechnology
- processing
- manufacturing

Prof. Dr. Mark Jackson

Guest Editor

Prof. Dr. Mark J. Jackson

School of Interdisciplinary Studies, College of Technology and Aviation,
Kansas State University, Aerospace and Technology Campus, Salina,
KS 67401, USA

Deadline for manuscript submissions

closed (31 January 2020)



Applied Sciences

an Open Access Journal
by MDPI

Impact Factor 2.5
CiteScore 5.5



mdpi.com/si/30480

Applied Sciences
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
applsci@mdpi.com

mdpi.com/journal/

[applsci](https://mdpi.com/journal/applsci)





Applied Sciences

an Open Access Journal
by MDPI

Impact Factor 2.5
CiteScore 5.5



[mdpi.com/journal/
applsci](https://mdpi.com/journal/applsci)



About the Journal

Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal *Applied Sciences* has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

Editor-in-Chief

Prof. Dr. Giulio Nicola Cerullo
Dipartimento di Fisica, Politecnico di Milano, Piazza L. da Vinci 32,
20133 Milano, Italy

Author Benefits

Open Access:

free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility:

indexed within Scopus, SCIE (Web of Science), Ei Compendex, Inspec, Embase, CAPIus / SciFinder, and other databases.

Journal Rank:

JCR - Q2 (Engineering, Multidisciplinary) / CiteScore - Q1 (General Engineering)